

Notice of References Cited	Application/Control No. 10/649,695		Applicant(s)/Patent Under Reexamination KOKUBUN ET AL.	
	Examiner John Hoffmann		Art Unit 1731	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-6,413,583 B1	07-2002	Moghadam et al.	427/249.15
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.